IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yeo, et al.

Docket No.: TSM03-0760

Serial No.: 10/

10/803,712

Art Unit: 1795

Filed:

March 18, 2004

Examiner:

Raymond, Brittany L.

For:

Immersion Fluid for Immersion Lithography, and Method of

Performing Immersion Lithography

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

RESPONSE UNDER 37 C.F.R. § 1.116

Dear Sir:

Applicants respectfully submit the following amendments and remarks in response to Examiner's Office Action dated April 29, 2009, which Action is made final. Applicants respectfully request that these amendments and remarks be entered pursuant to the provisions of 37 C.F.R. § 1.116, and respectfully request reconsideration of the rejected claims.

TSM03-0760 Page 1 of 17